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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 10/075,193  
Filing Date .... February 13, 2002  
Inventor .... Shenlin Chen et al.  
Assignee .... Micron Technology, Inc.  
Group Art Unit .... 2813  
Examiner .... Huynh, Y.  
Attorney's Docket No. .... M22-1927  
Title: Methods of Forming a Capacitor Structure

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**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References -See Attached Form PTO-1449

The Examiner's attention is directed to the references which are listed in the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.

This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing date of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: August 30, 2002

By: Jennifer J. Taylor  
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